

Fig. 1

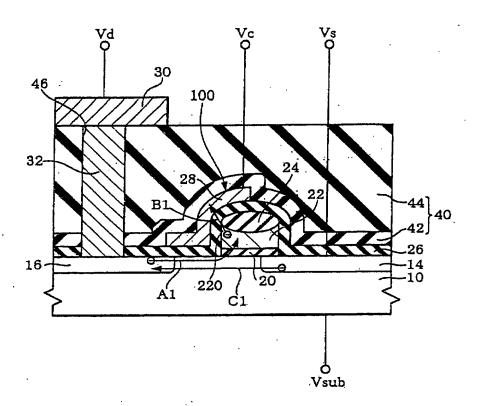
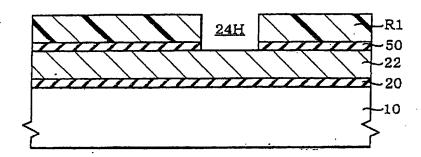
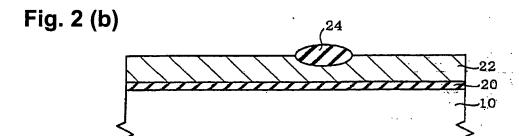




Fig. 2 (a)





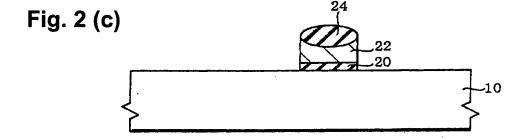




Fig. 3 (a)

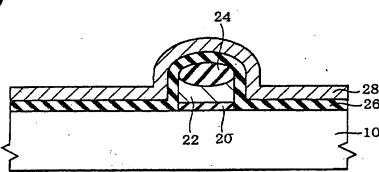
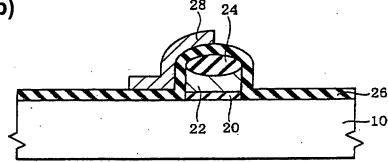


Fig. 3 (b)



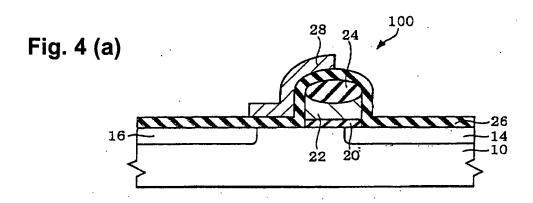
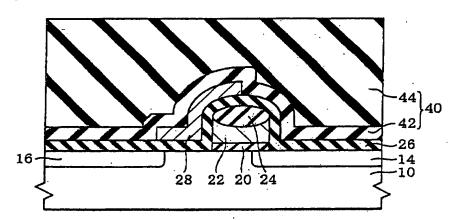
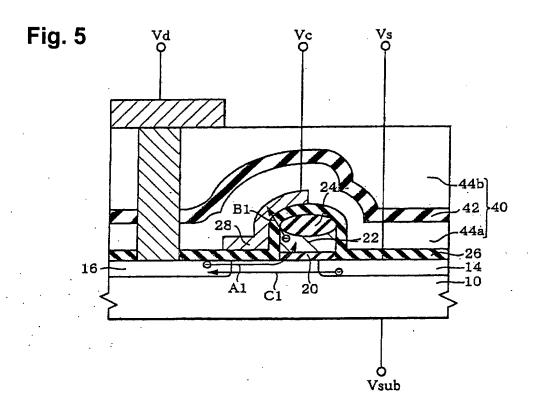
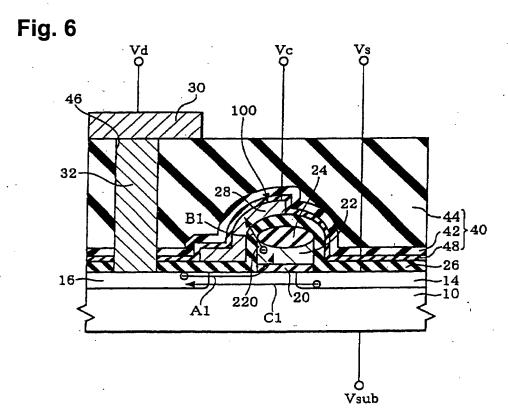


Fig 4 (b)









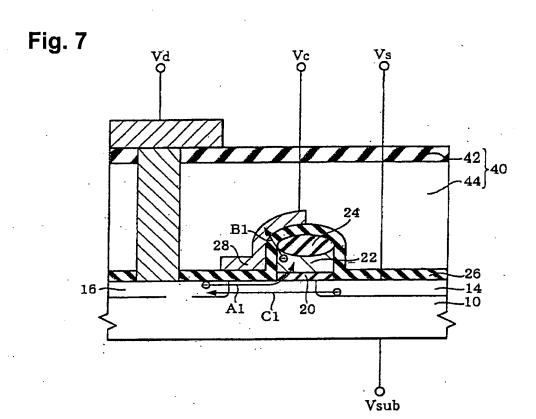


Fig. 8

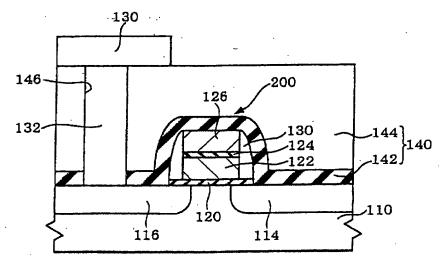




Fig. 9 (a)

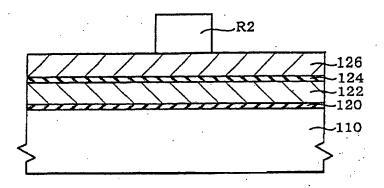
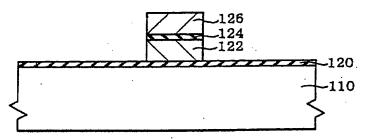


Fig. 9 (b)



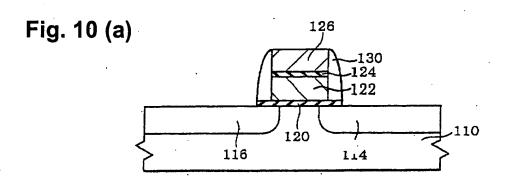


Fig. 10 (b)

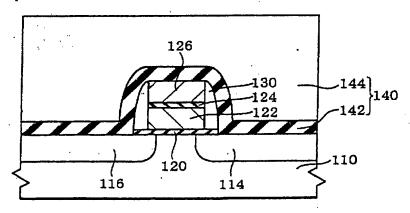
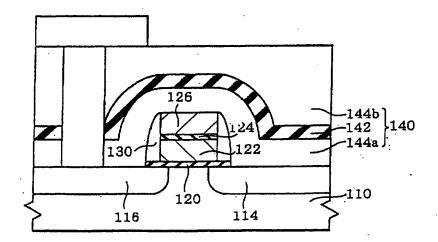
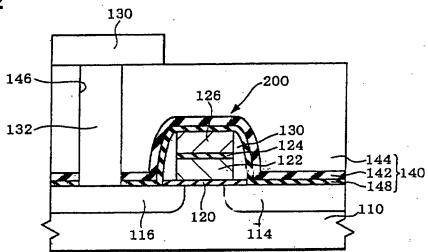


Fig. 11











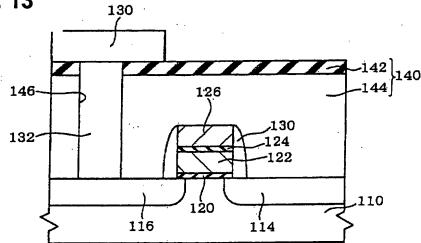


Fig. 14

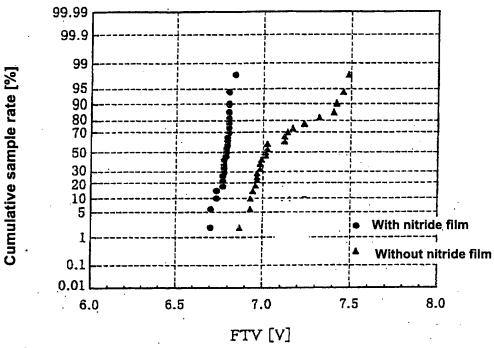


Fig. 15

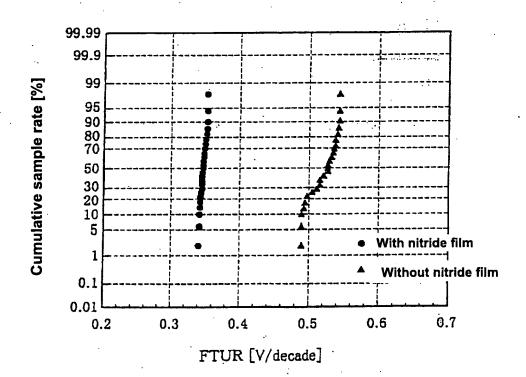
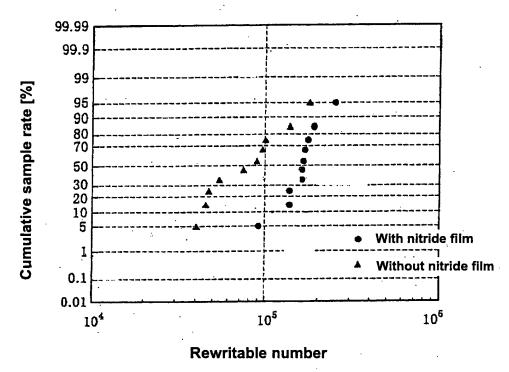
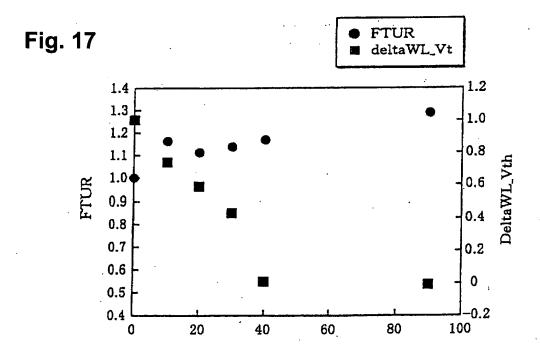




Fig. 16





Film thickness of silicon oxide layer [nm]



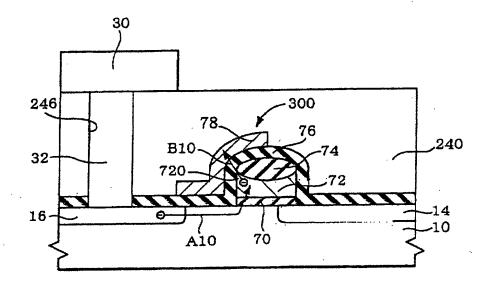


FIG. 18 PRIOR ART